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APPLICATION NO. FILING DATE FIRST NAMED INVENTOR ATTORNEY DOCKET NO. CONFIRMATION NO 09/448,756 11/24/1999 JUN KOYMA 0756-2070 5419 **EXAMINER** 22204 7590 06/25/2004 NIXON PEABODY, LLP BELL, PAUL A 401 9TH STREET, NW ART UNIT PAPER NUMBER **SUITE 900** WASHINGTON, DC 20004-2128 2675

DATE MAILED: 06/25/2004

Please find below and/or attached an Office communication concerning this application or proceeding.

	•	Application No.	Applicant(s)	
		09/448,756	KOYMA ET AL.	
	Office Action Summary	Examiner	Art Unit	
		PAUL A BELL	2675	
Period fo	The MAILING DATE of this communication a	ppears on the cover sheet with th	e correspondence address	
A SH THE - Exte after - If the - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REP MAILING DATE OF THIS COMMUNICATION ensions of time may be available under the provisions of 37 CFR of SIX (6) MONTHS from the mailing date of this communication. The period for reply specified above is less than thirty (30) days, a report of the provisions of the period for reply is specified above, the maximum statutory period reply within the set or extended period for reply will, by static reply received by the Office later than three months after the mailed patent term adjustment. See 37 CFR 1.704(b).	1. 1.136(a). In no event, however, may a reply be eply within the statutory minimum of thirty (30) of will apply and will expire SIX (6) MONTHS frute, cause the application to become ABANDO	days will be considered timely. Tom the mailing date of this communication. The mailing date of this communication.	
Status				
1)⊠	Responsive to communication(s) filed on 07	<u>April 2004</u> .		
· —		nis action is non-final.		
3)	Since this application is in condition for allow	ance except for formal matters, p	prosecution as to the merits is	
	closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.			
Disposit	ion of Claims			
5)□ 6)⊠ 7)□	Claim(s) 1-9,11-27 and 29-38 is/are pending 4a) Of the above claim(s) is/are withdr Claim(s) is/are allowed. Claim(s) 1-9,11-27 and 29-38 is/are rejected Claim(s) is/are objected to. Claim(s) are subject to restriction and	rawn from consideration.		
Applicat	ion Papers			
9)[The specification is objected to by the Examir	ner.		
10)	0)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.			
	Applicant may not request that any objection to the	•	` ·	
11)□	Replacement drawing sheet(s) including the correct The oath or declaration is objected to by the latest and the second se		• • • • • • • • • • • • • • • • • • • •	
Priority ι	under 35 U.S.C. § 119			
	Acknowledgment is made of a claim for foreig ☑ All b)☐ Some * c)☐ None of:		(a)-(d) or (f).	
	1. Certified copies of the priority docume			
	2. Certified copies of the priority docume			
	3. Copies of the certified copies of the pri	· ·	ived in this National Stage	
* 5	application from the International Bure See the attached detailed Office action for a list	` ''	ved	
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Attachmen	t(s)			
	e of References Cited (PTO-892)	4) Interview Summa		
3) 🛛 Infor	e of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449 or PTO/SB/08 r No(s)/Mail Date <u>25</u> .	Paper No(s)/Mail 5) Notice of Informa 6) Other:	Date Il Patent Application (PTO-152)	
D-1117	1			

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DETAILIED ACTION

1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

- (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claim 1-9, 11-27 and 29-38 are rejected under 35 U.S.C. 103(a) as being unpatentable over Matsumoto (5,323,042) in view of Adachi et al. (5,631,664) and Stewart (5,302,966).

With regard to claim 1 Matsumoto teaches an active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor (column 1, lines 5-12 figure 1, item 12, figure 4, item 6); and a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements (figure 1, item 13, figure 4, item 2 and 3), wherein each of said plurality of thin film transistors comprises a crystallized semiconductor layer (column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer and a gate electrode adjacent to said gate insulating film (figure 1, items 26, 24, and 22).

Matsumoto does not teach " a display medium comprising an emissive material and capable of electrically changing luminous strength disposed at each of said pixel electrodes". Matsumoto instead teaches a display medium being an liquid crystal which is not an "emissive material".

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Adachi et al. teaches a preference for EL or electroluminescence material which is a "emissive material" over liquid crystal material (See Adachi et al. column 1, lines 37-66). Stewart teaches with regards to using EL or LCD material in a matrix that, "Recently active matrix technology known in the liquid crystal display art has been applied to EL displays", (SEE Stewart column 1, lines 19-21).

Therefore it would have been obvious to one of ordinary skill in the art at the time the invention was made to modify the Matsumoto display medium to be EL instead of LC because Adachi et al. provided the suggestion and motivation to substitute EL for LC (See Adachi et al. column 1, lines 37-66) and still further Stewart provided the "reasonable expectation of success" in making the change (SEE Stewart column 1, lines 19-21).

With regard to claim 2 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said gate electrode is located over said semiconductor layer (See Matsumoto figure 1, items 26 and 11).

With regards to claim 3 Matsumoto as miodified by Adachi et al. and Stewart teaches wherein all of said plurality of thin film transistors are p-type (See Matsumoto column 5, line 6768).

With regard to claim 4 Matsumoto as modified by Adachi et al. and Stewart teaches wherein all of said plurality of thin film transistors are n-type (See Matsumoto column 5, line 6768).

With regard to claim 5 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

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With regard to claim 6 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 7 Matsumoto as modified by Adachi et al. and Stewart teaches an active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes, each of said switching elements comprising a thin film transistor (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, items 6 and 7), and a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements (See Matsumoto figure 1, item 13, figure 4, item 2 and 3), wherein each of said plurality of thin film transistors comprises a crystallized semiconductor layer (See Matsumoto column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer and a gate electrode adjacent to said gate insulating film (See Matsumoto figure 1, items 26, 24, and 22), wherein said crystallized semiconductor layer has source and drain regions and at least one lightly doped region (See Matsumoto column 3, lines 7-17).

With regard to claim 8 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

With regard to claim 9 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said source and drain regions and said at least one lightly doped region are doped with phosphorus (See Matsumoto column 4, lines 1-35).

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With regard to claim 11 Matsumoto teaches as modified by Adachi et al. and Stewart wherein said gate electrode is located over said semiconductor layer (See Matsumoto figure 1, items 26 and 11).

With regard to claim 12 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 13 Matsumoto as :modified by Adachi et al. and Stewart teaches an active matrix type display device comprising: a substrate having an insulating surface; a plurality of pixel electrodes arranged in a matrix form over said substrate; a plurality of switching elements operationally connected to said pixel electrodes (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, item 7), each of said switching elements comprising a thin film transistor (See Matsumoto figure 1, item 12:, figure 4, item 6), and a CMOS circuit comprising at least one n-channel type thin film transistor and one p-channel type thin film transistor (See Matsumoto column 2, line 68), wherein each of said n-channel and p-channel type thin film transistors comprises a crystallized semiconductor layer (See Matsumoto column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer and a gate electrode adjacent to said gate insulating film (See Matsumoto figure 1, items 26, 24, and 22).

With regard to claim 14 Matsumoto as modified by Adachi et al. and Stewart teaches wherein aid substrate is a glass substrate (See Matsumoto column 3, line 3).

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With regard to claim 15 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said gate electrode is located over said semiconductor layer (See Matsumoto figure 1, items 26 and 11).

With regard to claim 16 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 17 Matsumoto as modified by Adachi et al. and Stewart teaches an active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, item 6), each of said switching elements comprising a thin film transistor (See Matsumoto figure 1, item 12, figure 4, item 6), and a CMOS circuit comprising at least one n-channel type thin film transistor and one p-channel type thin film transistor (See Matsumoto column 2, line 68), each of said thin. film transistors comprising a crystallized semiconductor layer (See Matsumoto column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer and a gate electrode adjacent to said gate insulating film (See Matsumoto figure 1, items 26, 24, and 22), wherein said crystallized semiconductor layer has source and drain regions and at least one lightly doped region (See Matsumoto column 3, lines 7-17).

With regard to claim 18 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

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With regard to claim 19 Matsumoto teaches as modified by Adachi et al. and Stewart an active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, item 6), each of said switching elements comprising a thin film transistor (See Matsumoto figure 1, item 12, figure 4, item 7), and a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements (See Matsumoto figure 4, items 2 and 3), wherein each of the film transistors of said switching elements and said driver circuit comprises a crystallized semiconductor layer (See Matsumoto column 3, lines 5964), a gate insulating film adjacent to said crystallized semiconductor layer and agate electrode adjacent to said gate insulating film (See Matsumoto figure 1, items 26, 24, and 22).

With regard to claim 20 Matsumoto as :modified by Adachi et al. and Stewart teaches wherein said gate electrode is located over said semiconductor layer (See Matsumoto figure 1, items 26 and 11).

With regard to claim 21 Matsumoto as modified by Adachi et al. and Stewart teaches wherein all of said plurality of thin film transistors are p-type (See Matsumoto column 5, line 6768).

With regard to claim 22 Matsumoto as modified by Adachi et al. and Stewart teaches wherein all of said plurality of thin film transistors are n-type (See Matsumoto column 5, line 6768).

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With regard to claim 23 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

With regard to claim 24 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 25 Matsumoto as modified by Adachi et al. and Stewart teaches In regards to claim 25 An active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, item 6), each of said switching elements comprising a thin film transistor (See Matsumoto figure 1, item 12, figure 4, item 7), and a driver circuit comprising a plurality of thin film transistors for driving said plurality of switching elements (See Matsumoto figure 4, items 2 and 3), wherein each of the thin film transistors of the switching elements and the driver circuit comprises a crystallized semiconductor layer (See Matsumoto column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer, and a gate electrode adjacent to said gate insulating film (See Matsumoto figure 1, items 26, 24, and 22), wherein said crystallized semiconductor layer has source and drain regions and at least one lightly doped region (See Matsumoto column 3, lines 7-17).

With regard to claim 26 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

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With regard to claim 27 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said source and drain regions and said at least one lightly doped region are doped with phosphorus (See Matsumoto column 4, lines 1-35).

With regard to claim 29 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said gate electrode is located over said semiconductor layer (See Matsumoto figure 1, items 26 and 11).

With regard to claim 30 Matsumoto as modified by Adachi et al. and Stewart teaches In regards to claim 30 wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 31 Matsumoto as modified by Adachi et al. and Stewart teaches an active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, item 6), each of said switching elements comprising a thin film transistor (See Matsumoto figure 1, item 12, figare 4, item 7), and a CMOS circuit comprising at least one n-channel type thin film transistor and one p-channel type thin film transistor (See Matsumoto column 2, line 68), wherein each of the film transistors of the switching elements and said n-channel and p-channel type thin film transistors comprises a crystallized semiconductor layer (See Matsumoto column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer and a gate electrode adjacent to said gate insulating film See Matsumoto figure 1, items 26, 24, and 22).

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With regard to claim 32 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

With regard to claim 33 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said gate electrode is located over said semiconductor layer (figure 1, items 26 and 11).

With regard to claim 34 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 35 Matsumoto as modified by Adachi et al. and Stewart teaches an active matrix type display device comprising: a substrate having an insulating surface, a plurality of pixel electrodes arranged in a matrix form over said substrate, a plurality of switching elements operationally connected to said pixel electrodes (See Matsumoto column 1, lines 5-12 figure 1, item 12, figure 4, item 6), each of said switching elements comprising a thin film transistor (See Matsumoto figure 1, item 12, figure 4, item 7), and a CMOS circuit comprising at least one n-channel type thin film transistor and one p-channel type thin film transistor (See Matsumoto column 2, line 68), wherein each of the film transistors of the switching elements and said n-channel and p-channel type thin film transistors comprises a crystallized semiconductor layer (See Matsumoto column 3, lines 59-64), a gate insulating film adjacent to said crystallized semiconductor layer and a gate electrode adjacent to said gate insulating film (See Matsumoto figure 1, items 26, 24, and 22), and said crystallized

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semiconductor layer has source and drain regions and at least one lightly doped region (See Matsumoto column 3, lines 7-17).

With regard to claim 36 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said substrate is a glass substrate (See Matsumoto column 3, line 3).

With regard to claim 37 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line 60).

With regard to claim 38 Matsumoto as modified by Adachi et al. and Stewart teaches wherein said crystallized semiconductor layer comprises silicon (See Matsumoto column 3, line60).

3. Applicant's arguments with respect to claim 1 have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Paul Bell whose telephone number is (703) 306-3019.

If attempts to reach the examiner by telephone are unsuccessful the Technology Center 2600 Customer Service Office whose telephone number is (703) 306-0377 can help with any inquiry of a general nature or relating to the status of this application.

Any response to this action should be mailed to:

Commissioner of Patents and Trademarks Washington, D.C. 20231

Or Faxed to: (703) 872-9306

Or Hand-delivered to: Crystal Park II, 2121 Crystal Drive, Arlington, VA, Sixth Floor

(Receptionist)

Paul Bell

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June 18, 2004

CHANH NGUYEN